



VFCAL sensor test facilities

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October 6-8, 2008



Outline



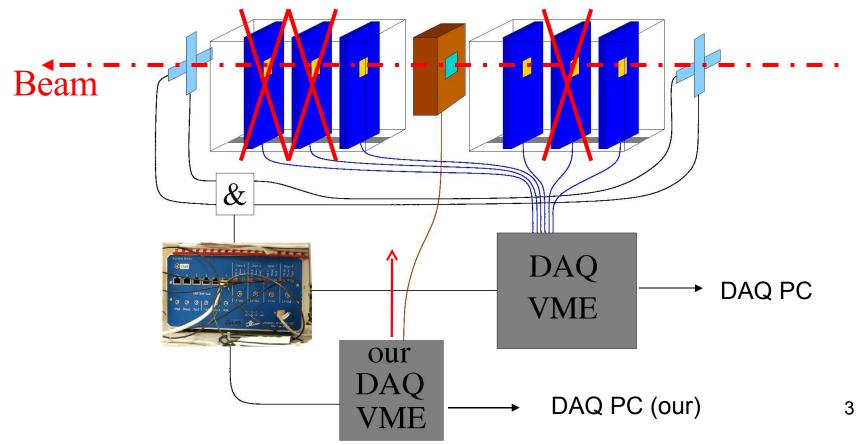
- Testbeam @ DESY-Hamburg
- Upgrade of DESY-Zeuthen setup:
- New triggering scheme
- TSC measuring setup
- Testbeam @ TU-Darmstadt
- Sensors under test
- Silicon Lab at Tel-Aviv University
- Summary



Testbeam @ DESY-Hamburg



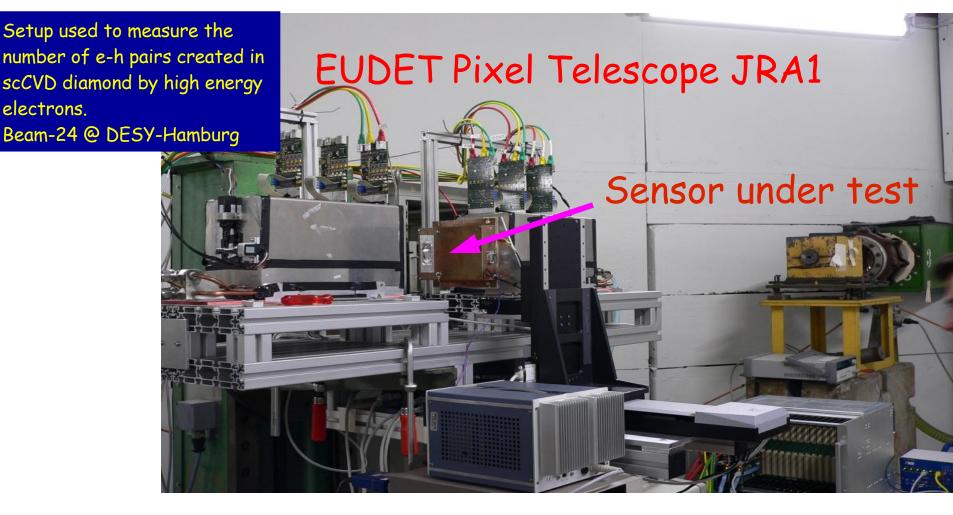
 CCD @ EUDET Pixel Telescope JRA1 for scCVD diamond, Si - space resolved hits





Testbeam @ Hamburg

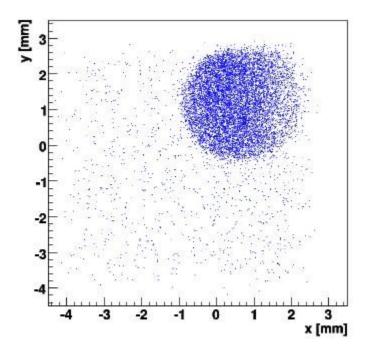






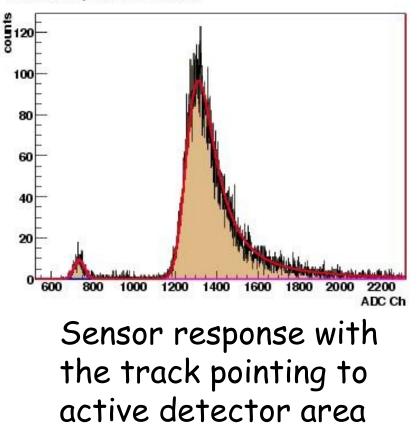
Data from testbeam @Hamburg

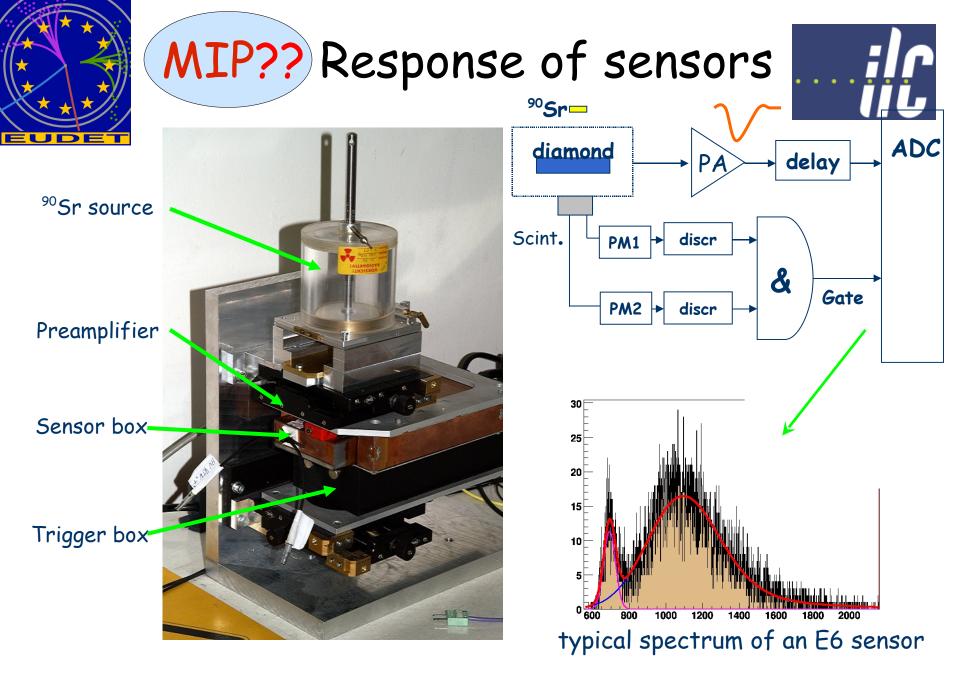


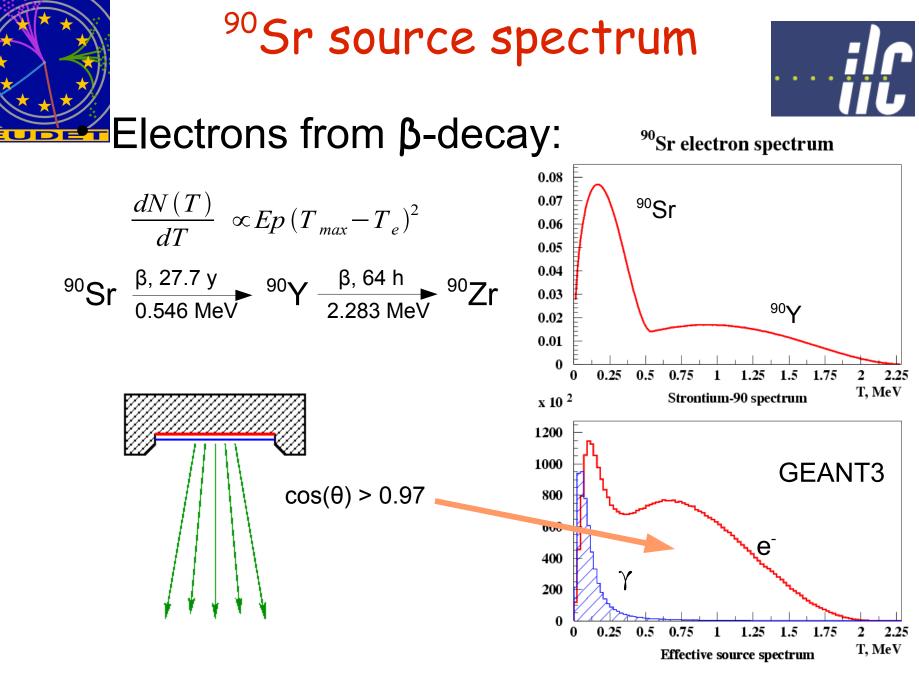


Reconstructed hits with detector signal

So14_10_spec_R1.5_1Track







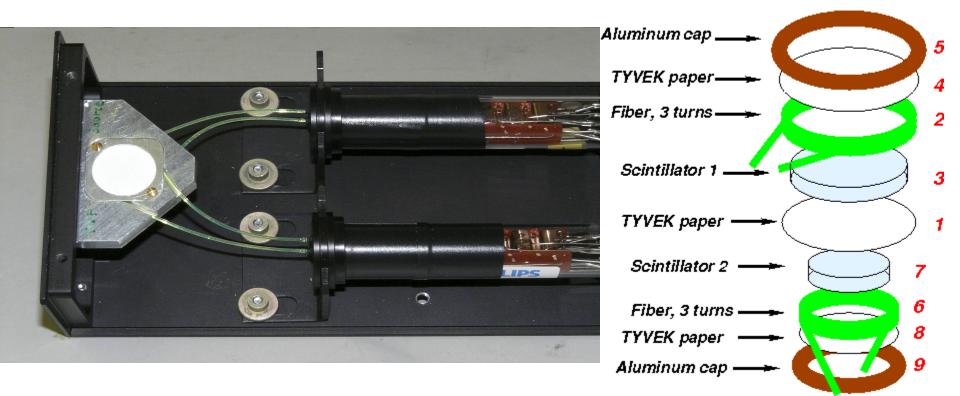
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Trigger box with new counters



Assembly of trigger box counter



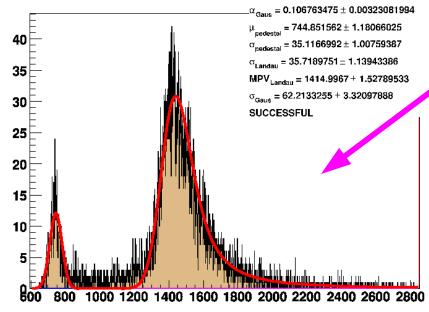
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⁹⁰Sr Setup: scCVD Diamond spectrum

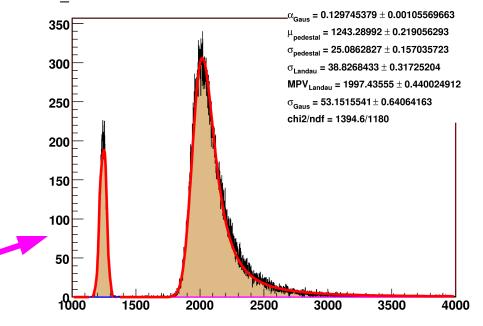


So14_04_100V_spec_00001



Before upgrade

100 K events run: 20 min data taking: run_00002



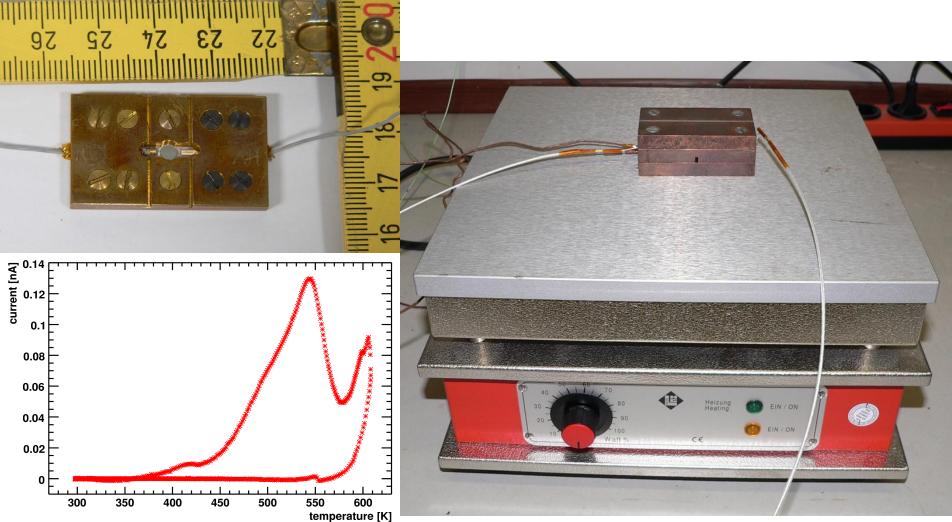
New trigger counters +optimized collimators

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TSC measurements setup

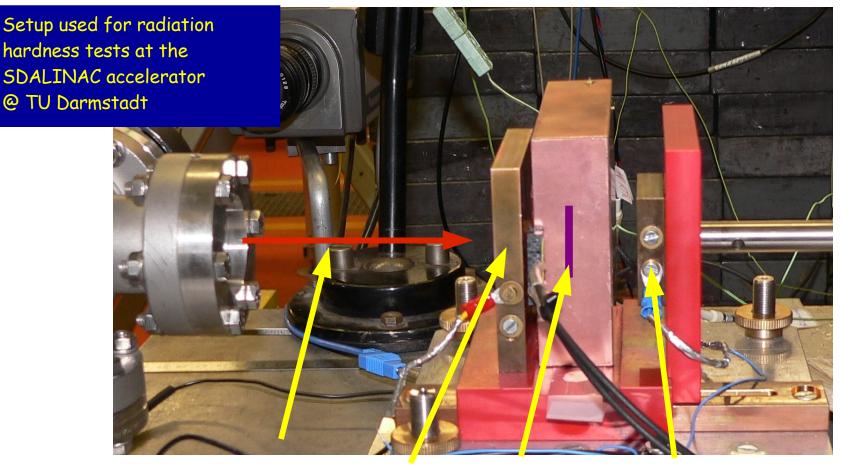






Testbeam Setup @ TU-Darmstadt





Beam Collimator Sensor Faraday Cup EUDET annual meeting - Amsterdam

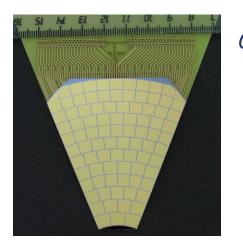
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Sensor Materials under Investigation

- GaAs (baseline):
 - semi-insulating GaAs, doped with Sn and compensated by Cr
 - produced by the Siberian Institute of Technology
 - available on (small) wafer scale
 - pCVD diamonds:
 - radiation hardness under investigation (e.g. LHC pixel detectors)
 - high mobility, low $ε_R = 5.7$, thermal conductivity availability on wafer scale
- SC CVD diamonds:
 - large and fast signal
 - available in sizes of few mm²
- New: Sapphire, Quartz:
 - relatively cheap
 - available in large sizes (<12")

CVD = Chemical Vapor Deposition



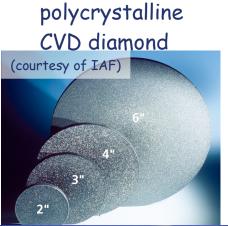
Single crystal CVD diamond

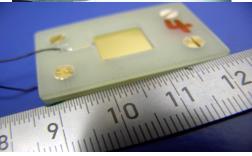


Sapphire









(from Nikko Hitech Int. webpage)



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Tel-Aviv Uni Silicon Lab



In the last months dedicated HEP lab building was designed (including a Silicon Lab for future detectors R&D).

a ~25 squared meter lab area will be dedicated only for the Silicon Lab.

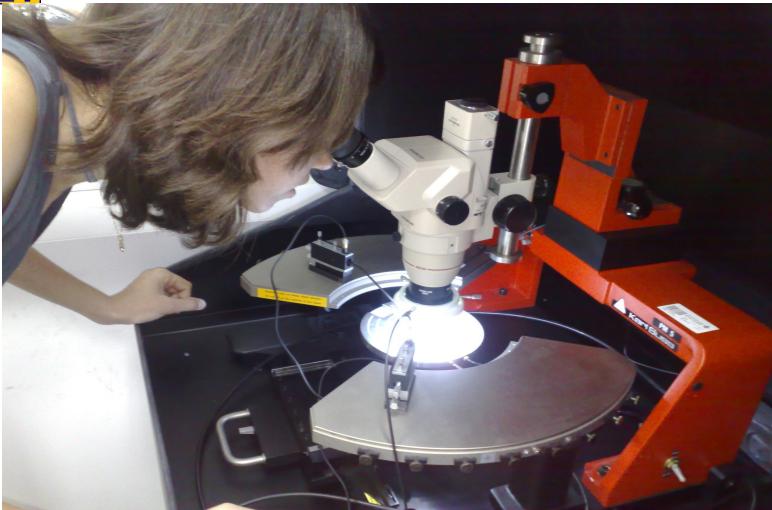
The new building is expected to be ready in the middle of 2009. The lab room was designed to accommodate future installation of a clean room infrastructure.

** Lab Equipment: fully equipped, computer monitored probe station. The equipment is set up in a temporary lab for I/V, C/V measurements.



Tel-Aviv Uni Silicon Lab





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Summary



- Laboratory infrastructure is created/improved/completed
- Testbeam equipment for sensor radiation hardness tests completed and used
- Testbeam equipment successfully operated in joint experiment with EUDET JRA1 pixel telescope
- VFCAL sensor test facilities are on schedule



Recent GaAs study



I-V B31 pad3 24C

